Fajun Yang

List of Publications by Year
in descending order

27 papers	750 citations	687363 13 h-index	752698 20 g-index
27 all docs	27 docs citations	27 times ranked	483 citing authors

#	Article	IF	Citations
1	Efficient scheduling approaches to time-constrained single-armed cluster tools with condition-based chamber cleaning operations. International Journal of Production Research, 2022, 60, 3555-3568.	7.5	5
2	Wafer sojourn time fluctuation analysis for time-constrained dual-arm multi-cluster tools with activity time variation. International Journal of Computer Integrated Manufacturing, 2021, 34, 734-751.	4.6	2
3	Modeling and Optimal Cyclic Scheduling of Time-Constrained Single-Robot-Arm Cluster Tools via Petri Nets and Linear Programming. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2020, 50, 871-883.	9.3	18
4	Wafer Residency Time Analysis for Time-Constrained Single-Robot-Arm Cluster Tools With Activity Time Variation. IEEE Transactions on Control Systems Technology, 2020, 28, 1177-1188.	5.2	11
5	Efficient Approach to Scheduling of Transient Processes for Time-Constrained Single-Arm Cluster Tools With Parallel Chambers. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2020, 50, 3646-3657.	9.3	13
6	Improved Jaya Algorithm for Flexible Job Shop Rescheduling Problem. IEEE Access, 2020, 8, 86915-86922.	4.2	12
7	Robust Scheduling of Time-Constrained Dual-Arm Cluster Tools With Wafer Revisiting and Activity Time Disturbance. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2019, 49, 1228-1240.	9.3	30
8	Solving Traffic Signal Scheduling Problems in Heterogeneous Traffic Network by Using Meta-Heuristics. IEEE Transactions on Intelligent Transportation Systems, 2019, 20, 3272-3282.	8.0	40
9	Flexible Job-Shop Rescheduling for New Job Insertion by Using Discrete Jaya Algorithm. IEEE Transactions on Cybernetics, 2019, 49, 1944-1955.	9.5	184
10	Petri Net-Based Efficient Determination of Optimal Schedules for Transport-Dominant Single-Arm Multi-Cluster Tools. IEEE Access, 2018, 6, 355-365.	4.2	5
11	Polynomial approach to optimal one-wafer cyclic scheduling of treelike hybrid multi-cluster tools via Petri nets. IEEE/CAA Journal of Automatica Sinica, 2018, 5, 270-280.	13.1	82
12	Wafer Sojourn Time Fluctuation Analysis of Time-Constrained Dual-Arm Cluster Tools With Wafer Revisiting and Activity Time Variation. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2018, 48, 622-636.	9.3	72
13	Optimal One-Wafer Cyclic Scheduling of Hybrid Multirobot Cluster Tools With Tree Topology. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2018, 48, 289-298.	9.3	11
14	Cyclic Scheduling Analysis of Single-arm Cluster Tools with Wafer Residency Time Constraint and Chamber Cleaning Operations. , 2018, , .		0
15	Efficient Approach to Cyclic Scheduling of Single-Arm Cluster Tools With Chamber Cleaning Operations and Wafer Residency Time Constraint. IEEE Transactions on Semiconductor Manufacturing, 2018, 31, 196-205.	1.7	14
16	Scheduling of Single-Arm Cluster Tools for an Atomic Layer Deposition Process With Residency Time Constraints. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2017, 47, 502-516.	9.3	115
17	Optimal One-Wafer Cyclic Scheduling of Time-Constrained Hybrid Multicluster Tools via Petri Nets. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2017, 47, 2920-2932.	9.3	21
18	Optimal scheduling analysis of treelike hybrid multi-cluster tools. , 2016, , .		0

#	Article	IF	Citations
19	Optimal one-wafer cyclic scheduling analysis of transport-dominant single-arm multi-cluster tools. , 2016, , .		1
20	Optimal scheduling of time-constrained single-arm cluster tools with wafer revisiting. , 2016, , .		2
21	Efficient and optimal scheduling of time-constrained hybrid multi-cluster tools in semiconductor industry. , 2016, , .		1
22	Petri net-based scheduling of time constrained single-arm cluster tools with wafer revisiting. Advances in Mechanical Engineering, 2016, 8, 168781401664650.	1.6	3
23	Petri Net-Based Optimal One-Wafer Cyclic Scheduling of Hybrid Multi-Cluster Tools in Wafer Fabrication. IEEE Transactions on Semiconductor Manufacturing, 2014, 27, 192-203.	1.7	41
24	Optimal scheduling of single-arm multi-cluster tools with two-space buffering modules. , 2014, , .		3
25	Petri Net-Based Polynomially Complex Approach to Optimal One-Wafer Cyclic Scheduling of Hybrid Multi-Cluster Tools in Semiconductor Manufacturing. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2014, 44, 1598-1610.	9.3	39
26	Optimal one-wafer cyclic scheduling analysis of hybrid multi-cluster tools with one-space buffering module. , 2014, , .		1
27	Optimal One-Wafer Cyclic Scheduling of Single-Arm Multicluster Tools With Two-Space Buffering Modules. IEEE Transactions on Systems, Man, and Cybernetics: Systems, 2014, 44, 1584-1597.	9.3	24